

Form PTO 1449  
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## LIST OF REFERENCES CITED BY APPLICANT

APPLICANT

Carole BAUBET, et al.

FILING DATE

June 28, 2006

GROUP

1794

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						
	AM						
	AN						

## FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION	
					YES	NO
	AO					
	AP					
	AQ					
	AR					
	AS					
	AT					
	AU					
	AV					

## OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)

	AW	Influence of Ar ion-beam assistance and annealing temperatures on properties of TiO <sub>2</sub> thin films deposited by reactive DC magnetron sputtering, Sung-Hwa Kim, et al., Elsevier, pp. 155-159, Thin Solid Films 475 (2005).	
	AX	DC reactive magnetron sputtering with Ar ion-beam assistance for titanium oxide films, S.-H. Kim, et al., Elsevier, pp. 457-464, Surface and Coatings Technology 158-159 (2002).	
	AY	The effect of the ion beam energy on the properties of indium tin oxide thin films prepared by ion beam assisted deposition, Li-Jian Meng, et al., Elsevier, pp. 1365-1369, Thin Solid Films 516 (2008).	
	AZ	Structure and properties of TiO <sub>2</sub> films prepared by ion beam assisted deposition, Xiaoling Cheng, et al., Elsevier, pp. 5552-5555, Surface Coatings & Technology 201 (2007).	<input type="checkbox"/> Additional References sheet(s) attached

Examiner

Date Considered

\*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.